

AUTHOR INDEX

Akila, R., 311
 Archer, P. B. M., 379
 Armstrong, B. M., 225
 Audet, S. A., 155, 287

Bayvel, P., 247
 Bearzotti, A., 43
 Bentley, R. E., 89

Caliendo, C., 43
 Campanella, L., 235
 Chadwick, A. V., 379
 Coles, G., 393

D'Amico, A., 43

Evans, N. J., 255

Fortunato, G., 43
 French, P. J., 121
 Futata, H., 1

Gamble, H. S., 225
 Göpel, W., 167
 Gotoh, M., 55

Halttunen, J., 335
 Hamakawa, Y., 263
 Harvey, I., 393
 Hayashi, K., 25
 Hetrick, R. E., 197
 Hisamoto, J., 301
 Hök, B., 67
 Huijsing, J. H., 109

Iiyama, S., 25
 Ishida, M., 101

Jacob, K. T., 311
 Jones, M. G., 215
 Jones, R. E., 135

Karube, I., 55
 Kimata, M., 263
 Kitagawa, H., 369
 Klein, C. F., 325
 Kodato, S., 209
 Kurumiya, Y., 345
 Kuwata, S., 301

Lian, W., 121
 Lindén, Y., 67
 Ling, E., 225
 Luntta, E., 335

Maenaka, K., 101
 Matsuguchi, M., 359
 Miasik, J. J., 379
 Miura, N., 301
 Moriga, N., 359
 Mukode, S., 1

Naden, J. M., 135
 Nakamura, T., 101
 Nakashima, N., 25
 Nakazawa, M., 345
 Nevell, T. G., 215
 Nuri, K., 345

Oda, S., 55
 Ohsakama, T., 101
 Okuyama, M., 263
 Ozaki, N., 25

Petty, M. C., 255

Regtien, P. P. L., 141
 Roberts, G. G., 255
 Russell, G. F., 89

Sadaoka, Y., 359
 Sakai, Y., 359
 Salardenne, J., 301
 Sammartino, M. P., 235
 Sato, K., 273
 Seki, A., 55
 Shimada, M., 359
 Shimizu, I., 55
 Suematsu, K., 273

Tamiya, E., 55
 Tamizi, M., 379
 Tamura, T., 273
 Tenerz, L., 67
 ten Kate, W. R. Th., 155, 287
 Thoma, P. E., 325
 Tirén, J., 67
 Togami, Y., 263
 Togawa, T., 273
 Toko, K., 25
 Tomassetti, M., 235

Uematsu, S., 263
 Usui, T., 345

van Oudheusden, B. W., 109

Velchev, N. B., 83

Wakefield, J., 225
 Watson, J., 393
 Wolffenbuttel, R. F., 13, 141
 Wright, J. D., 379

Yamafuji, K., 25
 Yamazoe, N., 301
 Yoshida, T., 25

SUBJECT INDEX

- β -alumina
 /Na₂SO₄ couple, SO_x ($x = 2, 3$) sensor using, 311
- Atomistic models
 and research trends; solid-state chemical sensors, 167
- Blood pH monitoring
 by use of null method, continuous, 27 273
- BSO-type crystals
 electro-optic coefficient in, with optical activity measurement and application to sensors, 247
- Calcium
 Li-Te and Ca-Te thin-film junctions as humidity sensors, 369
- Catalytic flammable gas sensors
 detection of H using, 215
- CCD image sensor
 pyroelectric infrared-, using LiTaO₃, 263
- Chemical sensors
 solid-state; atomistic models and research trends, 167
- Colour filtering element
 operation of Si, 13
- Contour detection
 option, integrated tactile imager with intrinsic, 141
- Doping-selective etching (DSE)
 fabrication of three-dimensional Si structures by means of, 67
- Electret
 and Th gas sensors, 325
- Electric characteristics
 of lipid cast membrane with single pore, effect of taste substances, on, 25
- Electromagnetic flow measurement
 effect of velocity profile on, 335
- Electro-optic coefficient
 in BSO-type crystals with optical activity measurement and application to sensors, 247
- Environmental chamber
 for characterization of gas sensors, development of, 393
- Enzyme-entrapping membranes
 for enzyme sensors, 235
- Enzyme sensors
 enzyme-entrapping membranes for, 235
- Flip-flop sensor
 modelling of, and optical pattern detector, 121
- Flow-direction sensor
 integrated Si, 109
- Fluorine
 solid-state O sensor using sputtered LaF₃ film, 301
- Gas-polarographic multifunctional sensor
 O-humidity sensor, 345
- Gas sensor(s)
 detection of H using catalytic flammable, 215
 development of environmental chamber for characterization of, 393
 electret and Rh, 325
 organometallic semiconductor, kinetic factors in response of, 379
- Germanium
 simple high-performance power sensor using μ c-Si:Ge thin films, 209
- Halltrons
 MOS; new relation for their use as sensors, 83
- Humidity sensor(s)
 Li-Te and Ca-Te thin-film junctions as, 369
 O-, gas-polarographic multifunctional sensor, 345
 based on organopolysiloxanes having hydrophilic groups, 359
 semiconductive, 1
- Hydrogen detection
 using catalytic flammable gas sensors, 215
- Hydrogen gas
 effects of on Pd/LB film/Si MIS devices, 255

- Hydrogen sensitivity
 - of Pd/SiO₂/Si structure; correlation with H-induced modifications on optical and transport properties of α -phase Pd films, 43
- Image sensor
 - pyroelectric infrared-CCD, using LiTaO₃, 263
- Imaging radiation
 - two-dimensional Si sensor for, 155
- ISFET
 - construction of amorphous Si, 55
- Kinetic factors
 - in response of organometallic semiconductor gas sensors, 379
- Lanthanum
 - solid-state O sensor using sputtered LaF₃ film, 301
- Lipid cast membrane
 - with single pore, effect of taste substances on electric characteristics of, 25
- Lithium
 - pyroelectric infrared-CCD image sensor using LiTaO₃, 263
 - Te and Ca-Te thin-film junctions as humidity sensors, 369
- Magnetic-field sensor
 - vibrating cantilever, 197
- Magnetotransistors
 - experimental investigation of operating principles of vertical, 101
- MIS devices
 - effects of H gas on Pd/LB film/Si, 255
- MOS Halltrons
 - new relation for their use as sensors, 83
- Nicrosil
 - sheathed mineral-insulated type N thermocouple probes for short-term variable-immersion applications to 1100 °C, 89
- Null method
 - continuous blood pH monitoring by use of, 273
- Operating principles
 - of vertical magnetotransistors, experimental investigation of, 101
- Optical activity
 - measurement and application to sensors, electro-optic coefficient in BSO-type crystals with, 247
- Optical pattern detector
 - modelling of flip-flop sensor and, 121
- Optical properties
 - H sensitivity of Pd/SiO₂/Si structure; correlation with H-induced modifications on, and transport properties of α -phase Pd films, 43
- Optically-addressed silicon strain sensor, 135
- Organometallic semiconductor gas sensors
 - kinetic factors in response of, 379
- Organopolysiloxanes
 - humidity sensors based on, having hydrophilic groups, 359
- Oxygen sensor
 - solid-state, using sputtered LaF₃ film, 301
- Oxygen-humidity sensor
 - gas-polarographic multifunctional sensor, 345
- Palladium
 - effects of H gas on Pd/LB film/Si MIS devices, 255
 - H sensitivity of Pd/SiO₂/Si structure; correlation with H-induced modifications on optical and transport properties of α -phase Pd films, 43
- pH monitoring
 - continuous blood, by use of null method, 273
- Power sensor
 - simple high-performance, using μ c-Si:Ge thin films, 209
- Pyroelectric infrared
 - CCD image sensor using LiTaO₃, 263
- Rhodium
 - gas sensors, electret and, 325
- Semiconductive humidity sensor, 1
- Sensor applications
 - processing high-purity Si used for, 287
- Silicon
 - colour filtering element, operation of, 13
 - contruction of amorphous Si ISFET, 55
 - effects of H gas on Pd/LB film/Si MIS devices, 255
 - fabrication of three-dimensional Si structures by means of doping-selective etching (DSE), 67

- flow-direction sensor, integrated, 109
- H sensitivity of Pd/SiO₂/Si structure; correlation with H-induced modifications on optical and transport properties of α -phase Pd films, 43
- optically-addressed, strain sensor, 135
- processing high-purity, used for sensor applications, 287
- sensor for imaging radiation, two-dimensional, 155
- simple high-performance power sensor using μ c-Si:Ge thin films, 209
- temperature sensor, novel polycrystalline, 225
- SO_x sensor
 - using β -alumina/Na₂SO₄ couple, ($x = 2, 3$), 311
- Sodium
 - SO_x ($x = 2, 3$) sensor using β -alumina/Na₂SO₄ couple, 311
- Strain sensor
 - optically-addressed Si, 135
- Tactile imager
 - integrated, with intrinsic contour detection option, 141
- Tantalum
 - pyroelectric infrared-CCD image sensor using LiTaO₃, 263
- Taste substances
 - effect of, on electric characteristics of lipid cast membrane with single pore, 25
- Tellurium
 - Li-Te and Ca-Te thin-film junctions as humidity sensors, 369
- Temperature sensor
 - novel polycrystalline Si, 225
- Thermocouple probes
 - microsil-sheathed mineral-insulated type N, for short-term variable-immersion applications to 1100 °C, 89
- Transport properties
 - H sensitivity of Pd/SiO₂/Si structure; correlation with H-induced modifications on optical and, of α -phase Pd films, 43
- Variable-immersion applications
 - short-term, to 1100 °C, microsil-sheathed mineral-insulated type N thermocouple probes for, 89
- Velocity profile
 - effect of, on electromagnetic flow measurement, 335
- Vibrating cantilever magnetic-field sensor, 197

